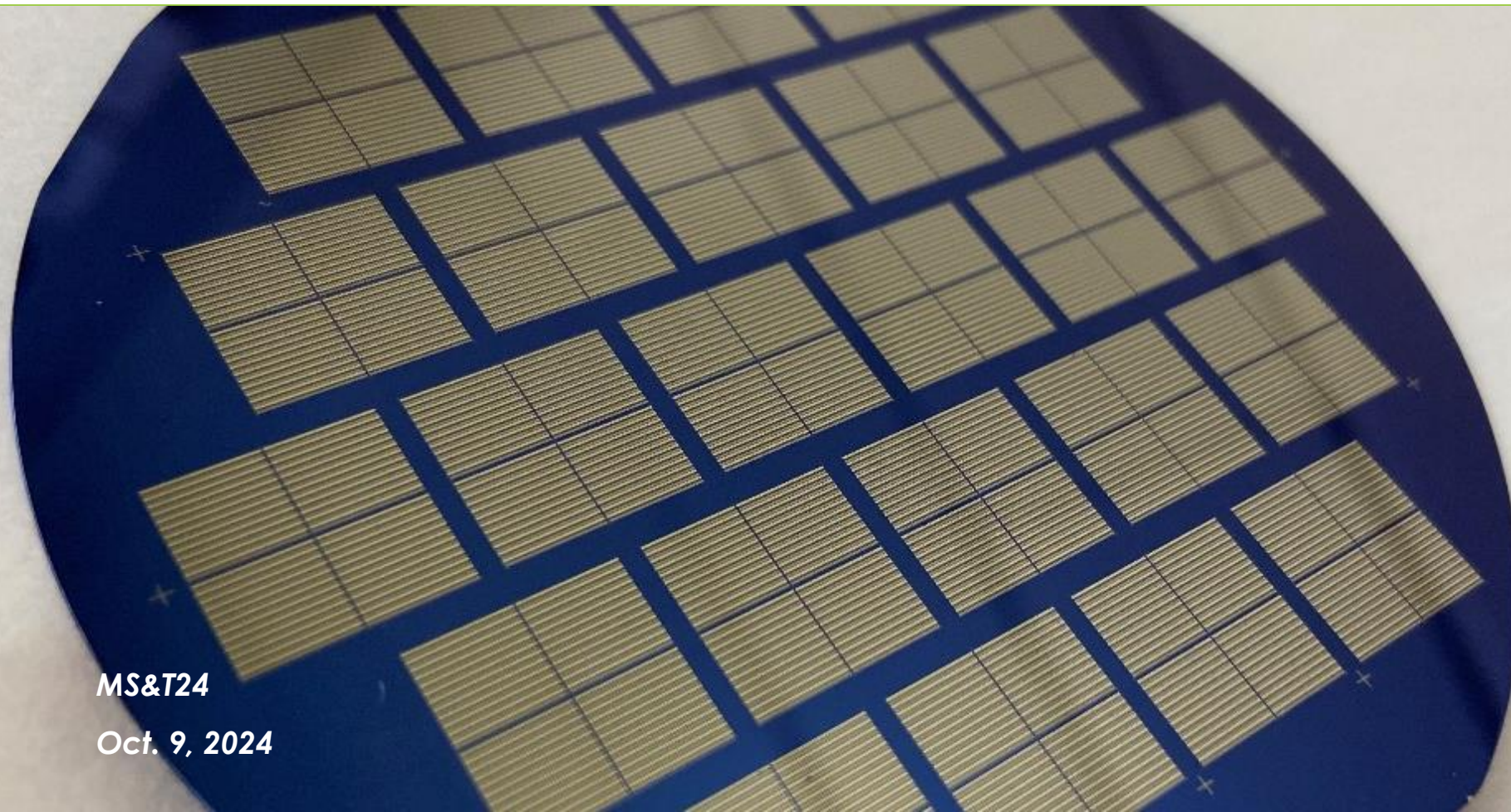


2D Amorphous Carbon Dielectric Prepared from Solution Precursor for Nanoelectronics



Viet Hung Pham

Research Engineer, NETL Support Contractor



MS&T24

Oct. 9, 2024

Disclaimer



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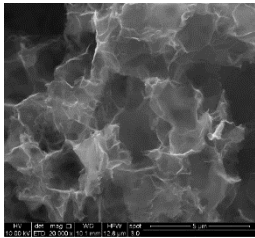
³University of Illinois at Urbana-Champaign, Champaign, IL 61820, USA

- Introduction
- Synthesis, Characterization, and Optimization of Solution Precursors and 2D Amorphous Carbon
- 2D Amorphous Carbon Dielectrics for Next Generation Microelectronic Devices
- Summary
- Acknowledgments

High Value Carbon Materials & Enabling Technologies

Carbon Materials of Diverse Structures & Properties from Domestic Feedstocks

3D Few-Layer Graphene

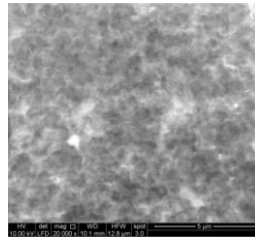


Graphite



Coal & Mining Waste,
Petroleum, Biomass,
Plastic Waste

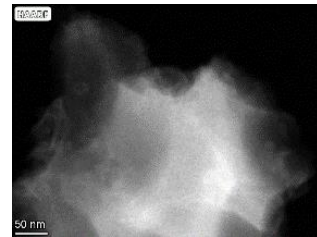
Graphene Oxide



Carbon
Quantum Dots



Graphene
Nanoflakes



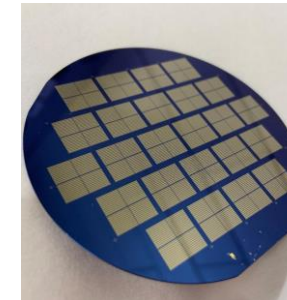
Porous Carbons



Energy Storage



Carbon
Electronics



Construction
Materials



Energy Consumption & CO₂ Emissions of Modern Computing

Efficient Microelectronic Devices Needed to Reduce Energy Consumption & Emissions

Forbes

Deep Learning's Carbon Emissions Problem

Rob Toews Contributor
I write about the big picture of artificial intelligence.

Jun 17, 2020, 11:54am EDT

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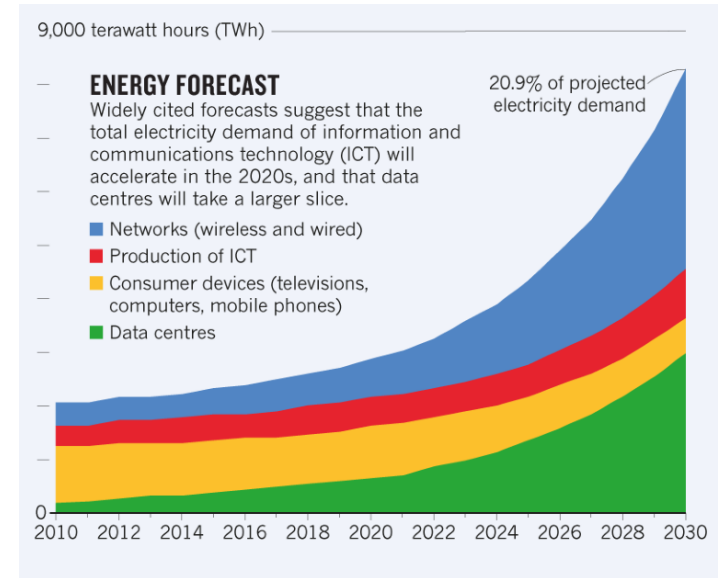
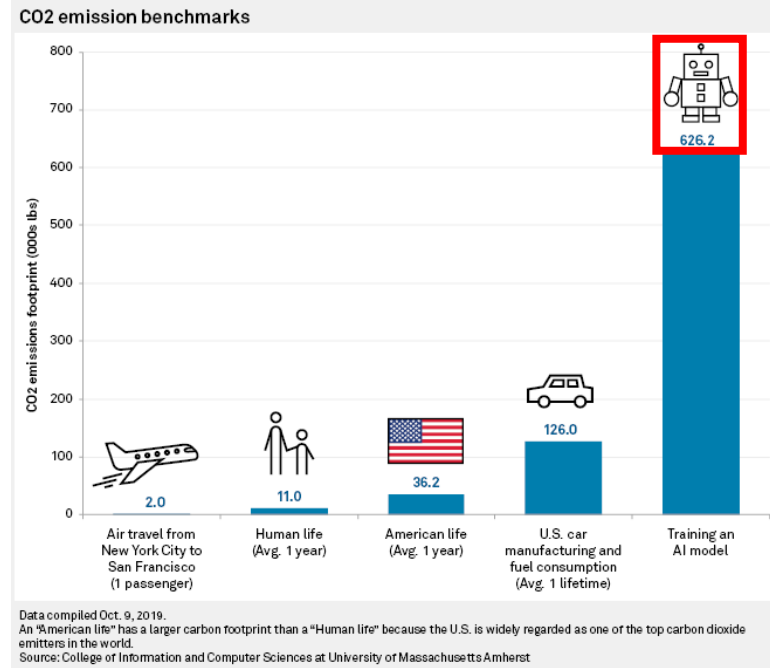
ARTIFICIAL INTELLIGENCE

We're getting a better idea of AI's true carbon footprint

AI startup Hugging Face has undertaken the tech sector's first attempt to estimate the broader carbon footprint of a large language model.

By Melissa Heikkilä | November 14, 2022

WOW!
500 metric tons of CO₂ = 600 flights between London and New York



Data centers:

- 1–1.5% of global electricity demand
- ~0.3% overall carbon emissions
- Global Information and Communication Information sector: 1.4% greenhouse gas emissions

Nature **561**, 163-166 (2018); <https://www.iea.org/reports/data-centres-and-data-transmission-networks>; www.spglobal.com/; www.forbes.com/; www.technologyreview.com/; Nature Climate Change **12**, 518–527 (2022).

Memristors for Modern Computing

IEEE Spectrum

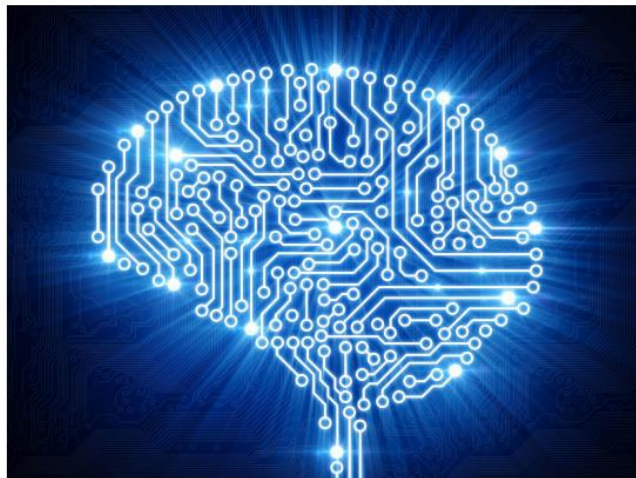
NEWS ARTIFICIAL INTELLIGENCE

Memristors Run AI Tasks at 1/800th Power

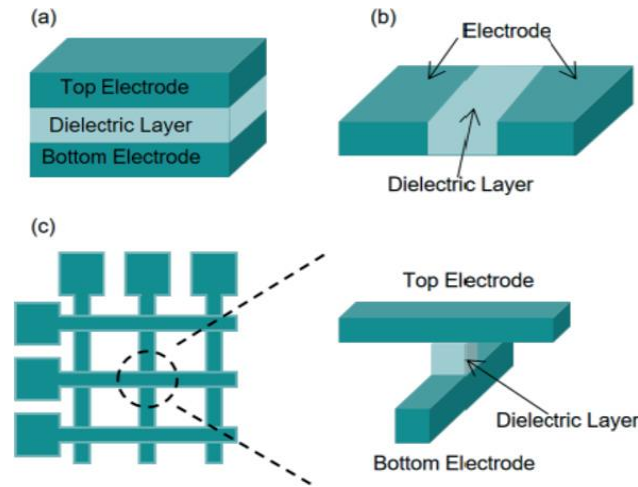
These brain-mimicking devices boast tiny energy budgets and hardened circuits

BY CHARLES Q. CHOI
04 JAN 2023

Charles Q. Choi is a Contributing Editor for IEEE Spectrum.



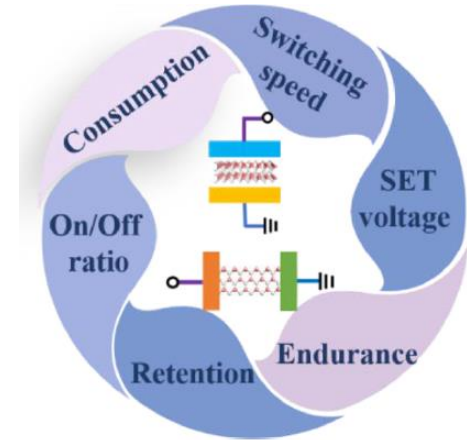
<https://spectrum.ieee.org/memristor-devices-ai#:~:text=Memristors%2C%20or%20memory%20resistors%2C%20are,both%20compute%20and%20store%20data.>



Memristor structure

(https://doi.org/10.1007/978-981-19-1673-1_77)

- Memristor, or memory resistor, is a two-terminal device consisting of a sandwiched structure of electrode/switching layer/electrode.
- The resistance of a memristor changes depending on the direction and amount of current flowing through it. A memristor's resistance value is maintained even after the power is turned off.



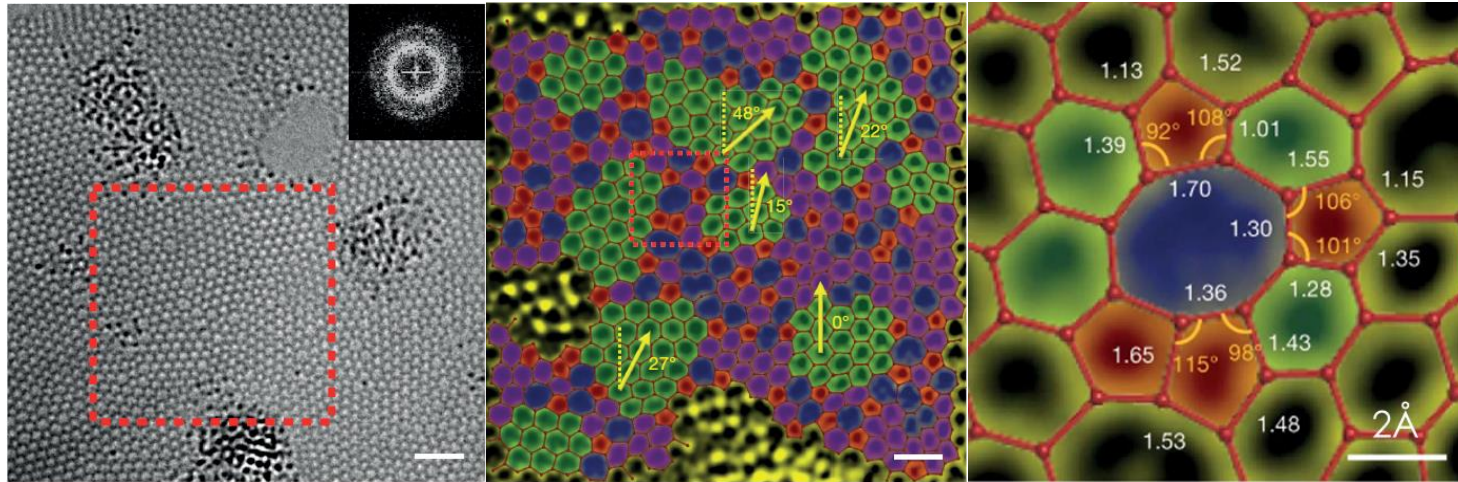
High performance of memristors based on 2D materials

(*J. Phys. Chem. Lett.* 2022, 13, 7130–7138)

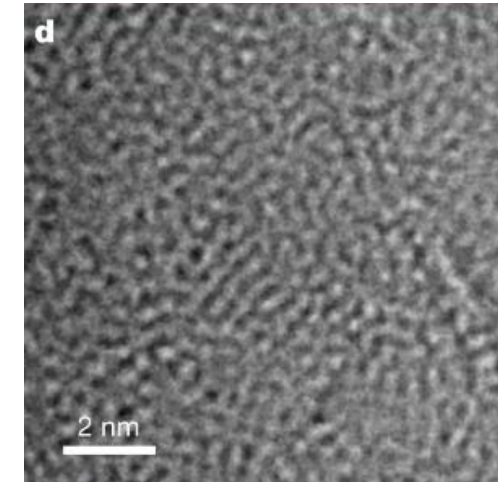
- Memristor's advantage: non-volatile, low energy consumption, fast reading and writing, high miniaturization.
- Atomically thin 2D materials are ideal switching layer with high-performance resistive switching characteristics, such as high on/off ratios, low set/reset voltages, good retention and endurance, fast switching speed, and low power and energy consumption.

2D Amorphous Dielectrics as Switching Layers

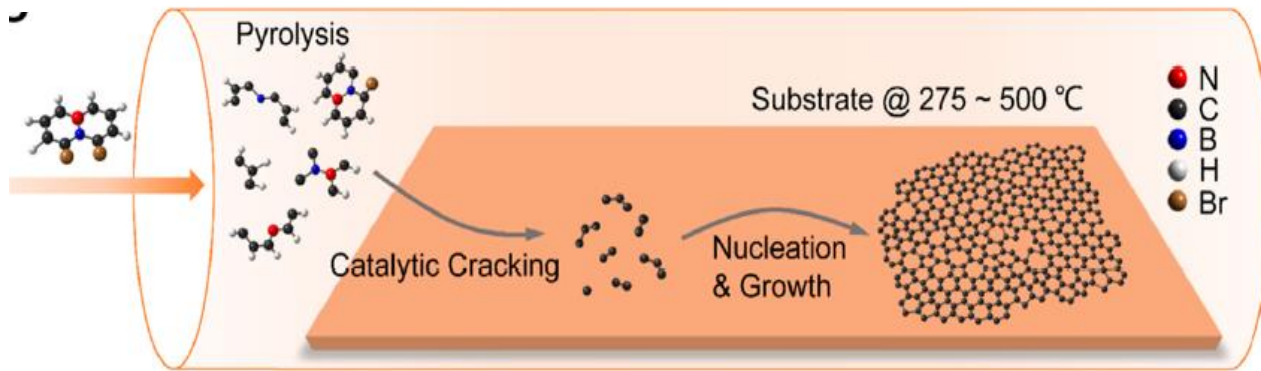
Significant Limitations of Existing Vacuum Deposition Methods



2D monolayer amorphous carbon (MAC).



2D amorphous boron nitride.



Schematic of the amorphous carbon growth using the cyclic aromatic molecule as the precursor.

Significant limitations:

- Limited spatial uniformity and area coverage
- No precise control of film thickness, especially beyond first monolayer
- Limited demonstration for device applications

ACS Nano 2023, **17**, 24468–24478
Nature 2020, **577**, 199–203; Nature 582, 511–514 (2020)

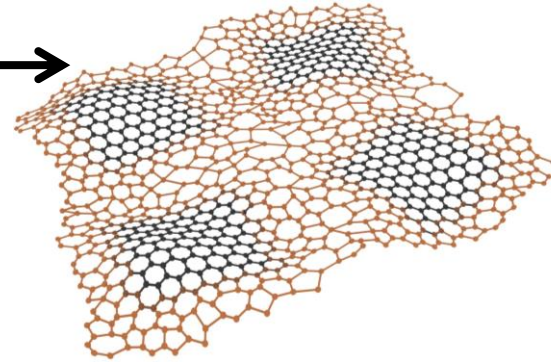
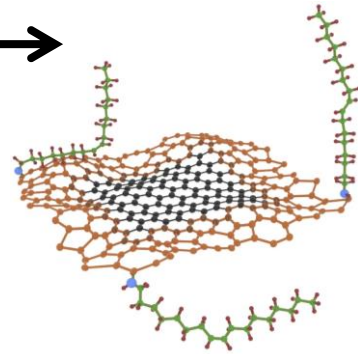
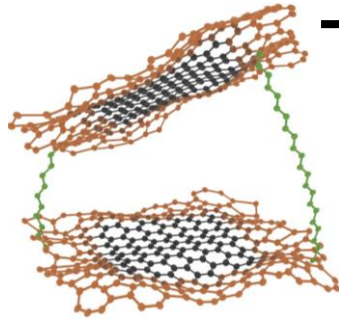
Can We Make Improved Electronic Materials from Coal?

Coal as Feedstock for Low-Cost, Scalable Production of 2D Dielectrics

Nanoscale graphitic domains

Acids/functionalization

Assembly/annealing

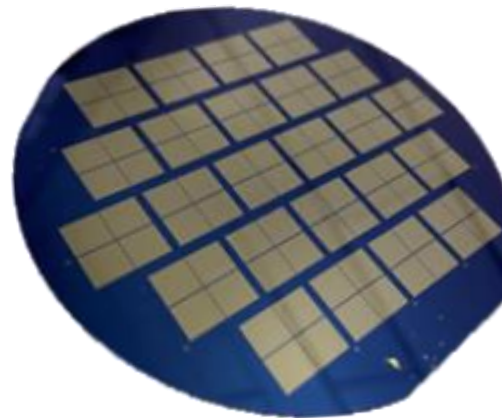


Advantages:

- Coal = small graphitic/aromatic domains, easy to extract
- Size/chemistry/properties ideal for thin film, non-conductive materials
- Solution precursors for scalable production with precise control of thickness
- Inexpensive, can make 1000s of prototypes
- Domestically sourced feedstock



1 L of Carbon Quantum Dots.



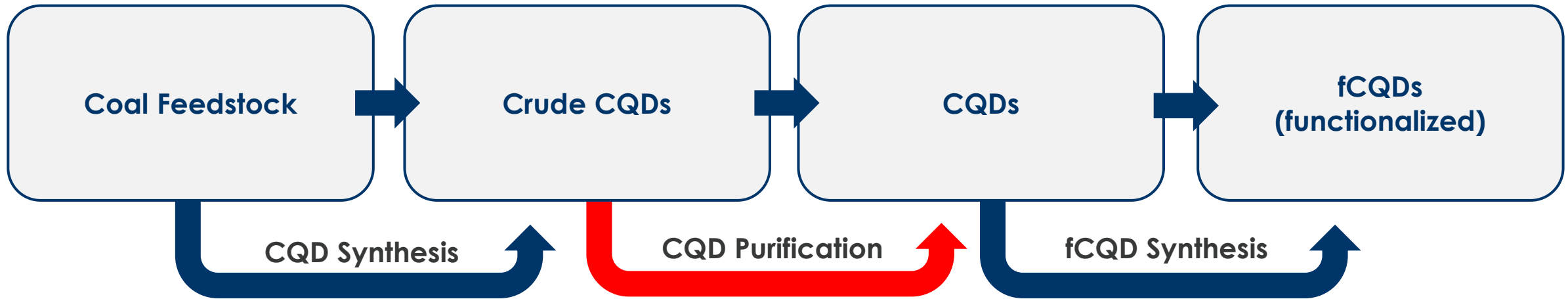
3-inch Memristor Prototype (~24,000 devices).

U.S. patent application No. 17/707,521
Communications Engineering 2, 93 (2023).

Synthesis and Functionalization of CQDs

Optimizing Processes to Produce the Perfect Precursor for 2D Carbon

Synthetic Pathway for Carbon Materials for Microelectronics



Challenges:

- Impurities of coal feedstock → purification needed
- Variation in size of as-synthesized carbon quantum dots (CQDs) → non-uniform carbon film → size exclusion needed
- Highly oxygenated, highly hydrophilic → not compatible with semiconductor device fabrication process → functionalization needed

Synthesis and Functionalization of CQDs

Synthesis and Purification of CQDs



Coal feedstock.

Concentrated $H_2SO_4 + HNO_3$, 100 °C, 24 h

Purification (acid washing + cross-flow ultrafiltration 8 times → removing 99.9999% contaminants)



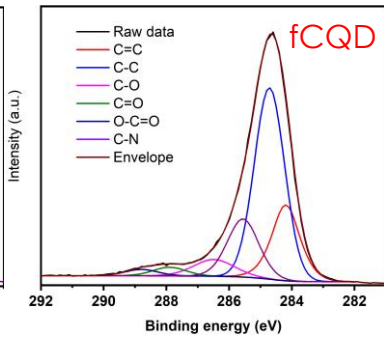
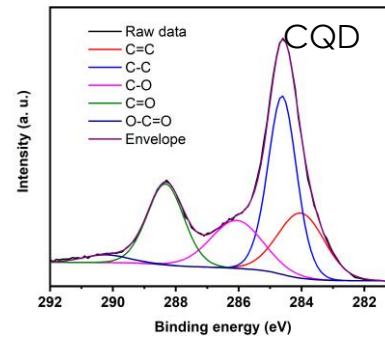
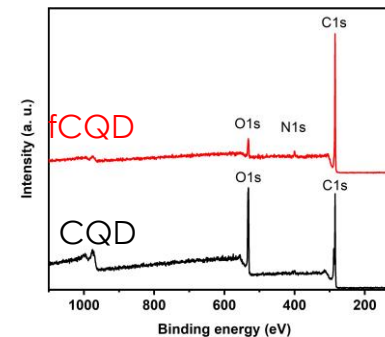
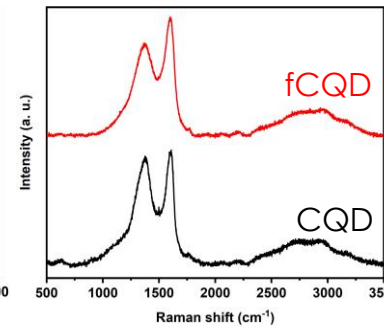
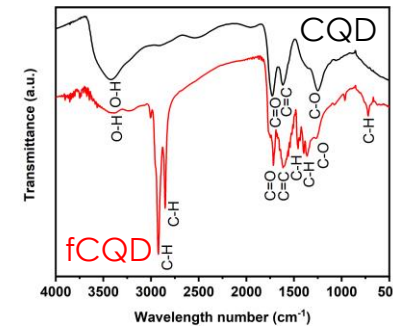
CQDs solution.

wt.%	Blue Gem Coal Fine	Coal Char*
Fixed C	61.68	95.89
Volatiles	36.66	1.52
Ash	1.66	2.59
C	81.19	94.82
O	9.39	0.08
N	2.12	1.67
H	4.88	0.31
S	0.76	0.53
SiO ₂	0.61	0.72
Cl, F, Hg	trace	trace

Al	0.19	0.31
Ti	0.015	0.017
Fe	0.20	0.42
Ca	0.084	0.16
Mg	0.019	0.028
K	0.027	0.032
Na	0.023	0.022
P	0.0023	0.0028
Sr	0.011	0.018
Ba	0.0077	0.010
Mn	0.00031	0.0029

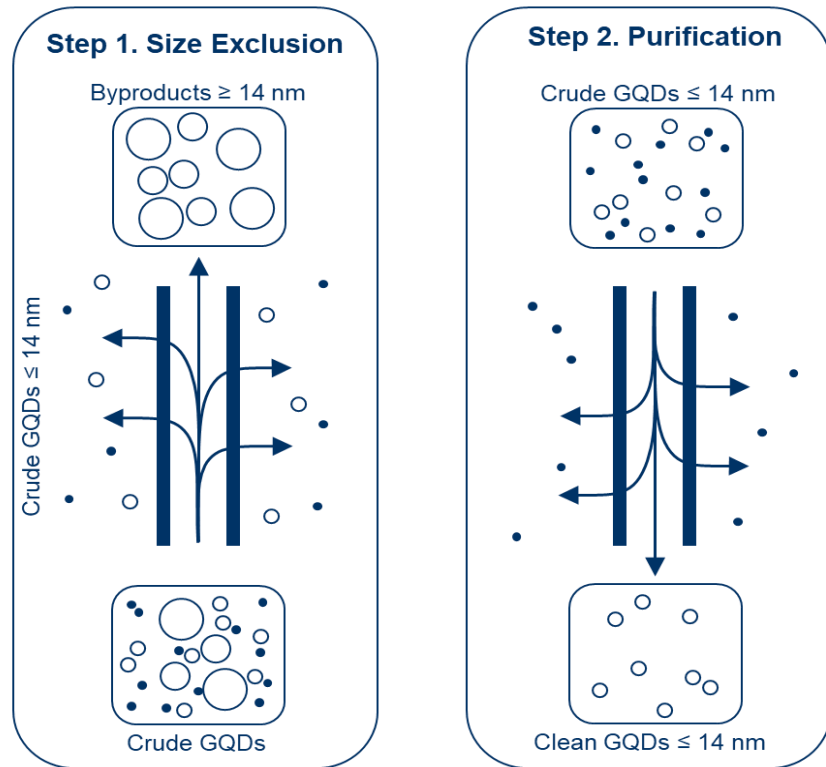
wt.%**	CQD	fCQD
C	61.7	85.1
O	38.3	11.1
N	-	3.8

**H not analyzed.



Synthesis and Functionalization of CQDs

Size Exclusion and Purification Using Cross-Flow Ultrafiltration



- Oxidized carbon particles, large CQDs, insolubilized minerals.
- CQDs.
- Water soluble mineral salts and oxidized polycyclic aromatic hydrocarbons (PAHs).

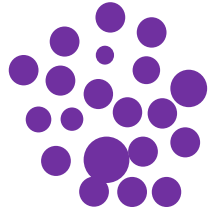
- **Step 1. Size exclusion:** cross-flow ultrafiltration using 50 kDa membrane with pore size of ~ 14 nm and collecting solution passed through membrane.
- **Step 2. Purification:** multiple cycles washing with acid (HCl) and then with water with cross-flow ultrafiltration using 3 kDa membrane with pore size of ~ 1.5 - 2.0 nm. 99.9999% of contaminants could be removed by repeating washing 8 times.

Synthesis and Functionalization of CQDs

Size Exclusion by Cross-Flow Ultrafiltration



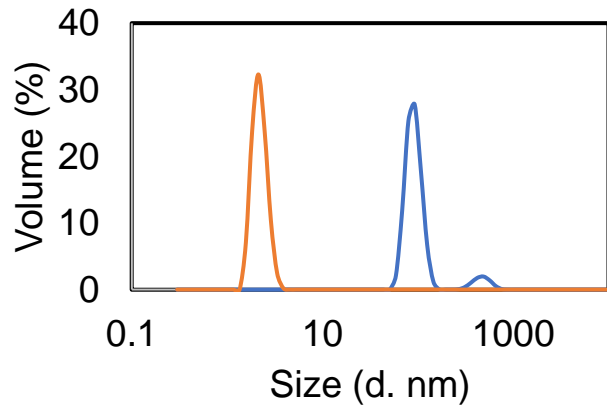
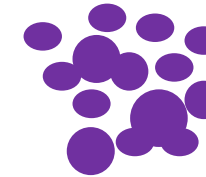
$\text{H}_2\text{SO}_4:\text{HNO}_3$ 3:1
100 °C, 24 hrs



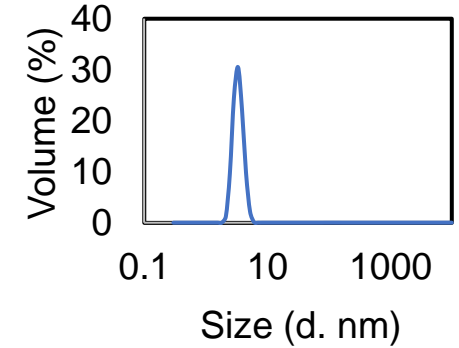
Dilution,
neutralization



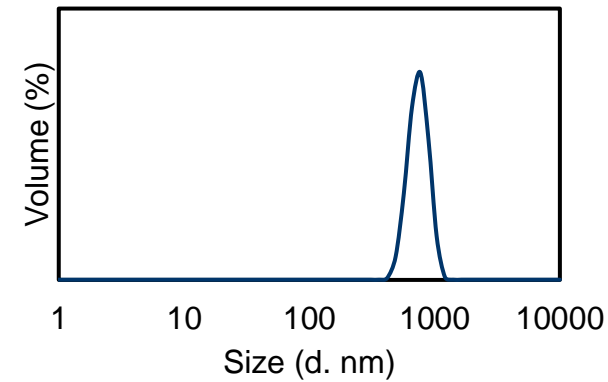
Cross-flow
ultrafiltration
using 50 kDa
membrane



Particle size distribution of crude GQDs analyzed by dynamic light scattering (DLS).

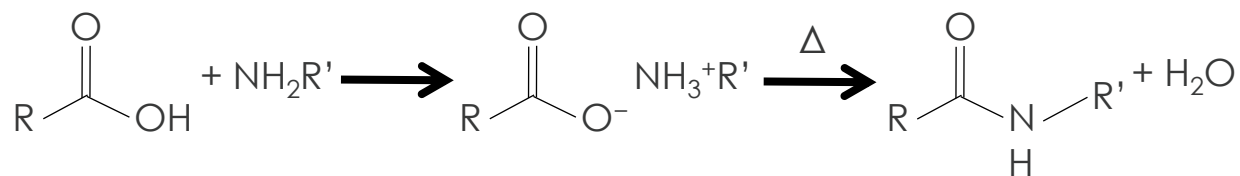


Particle size distribution of purified GQDs analyzed by DLS.



Synthesis and Functionalization of CQDs

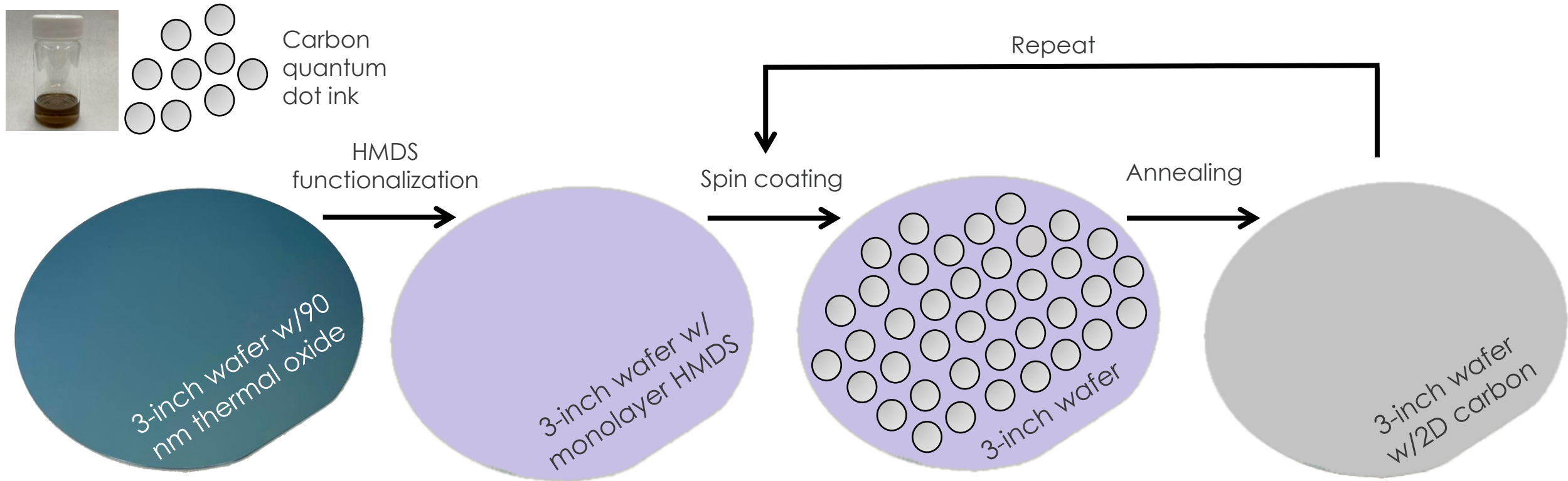
Functionalization of CQDs



- Functionalization to achieve right surface chemistry for stable dispersion in organic solvents compatible with device fabrication.

Scalable Production of 2D Amorphous Carbon

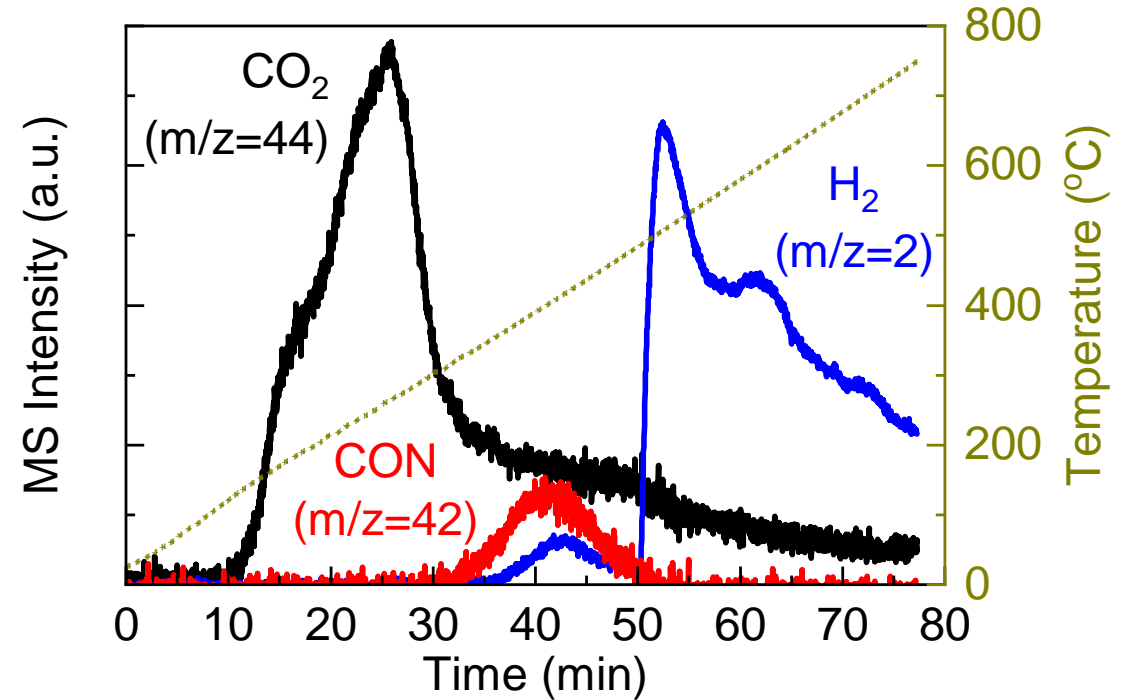
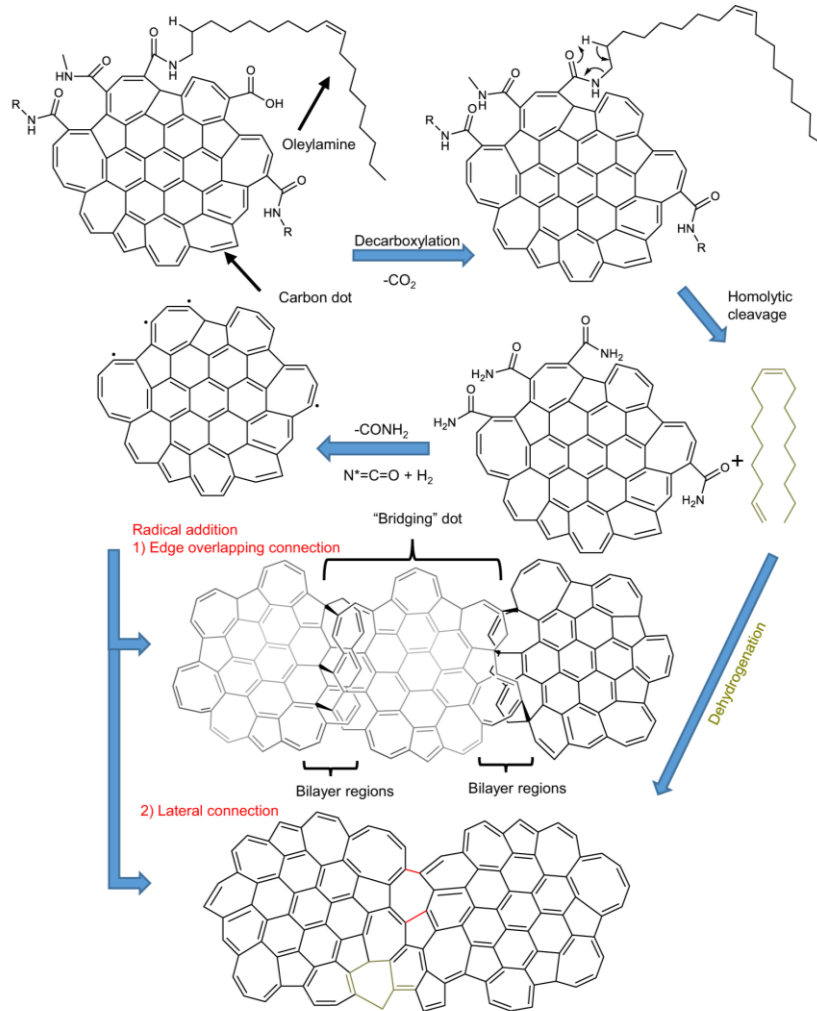
Low-Cost Fabrication of Large Area Continuous 2D Amorphous Carbon



Favorable interaction with hexamethyldisilazane (HMDS) promotes alignment of CQDs parallel to the wafer surface.

Carefully controlled surface chemistry and meticulously formulated precursor ink for the formation of high quality, continuous 2D amorphous films and device fabrication.

Coalescence of CQDs via Cleavage of Amide Bond



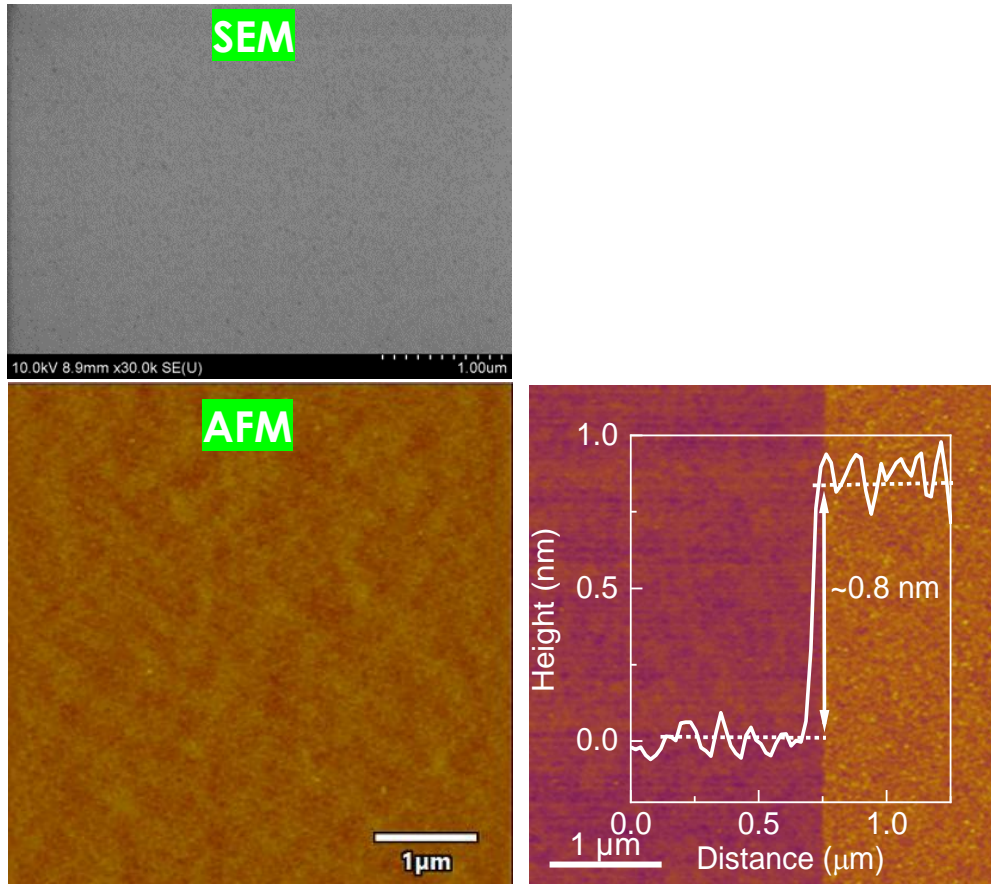
Similar to pyrolytic nylon decomposition:

- NH-CH₂ bond cleaved in the β position
- Cleavage of the C-CO amide bond and evolution of a CONH₂ fragment
- Radical addition to form film

Variation in 2D Carbon Film Quality

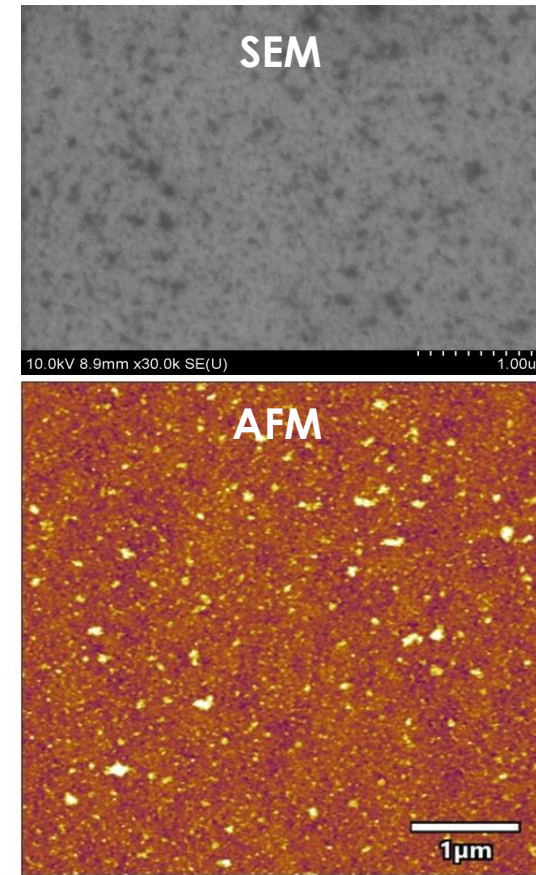
Inconsistent 2D Carbon Quality from Variation in CQD Precursors

Representative high quality 2D amorphous carbon
from size exclusive, high purified fCQDs



Root mean square (RMS) \sim 0.1 – 0.2 nm

Representative low quality 2D amorphous
carbon from as-synthesized fCQDs

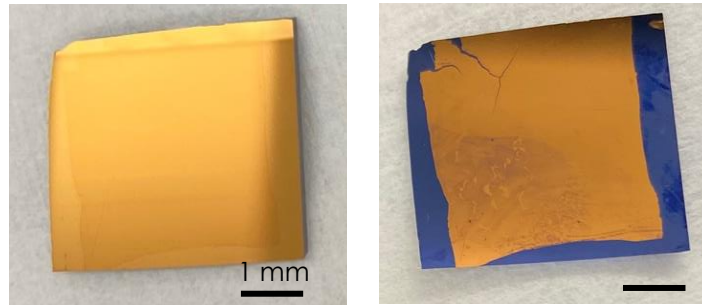
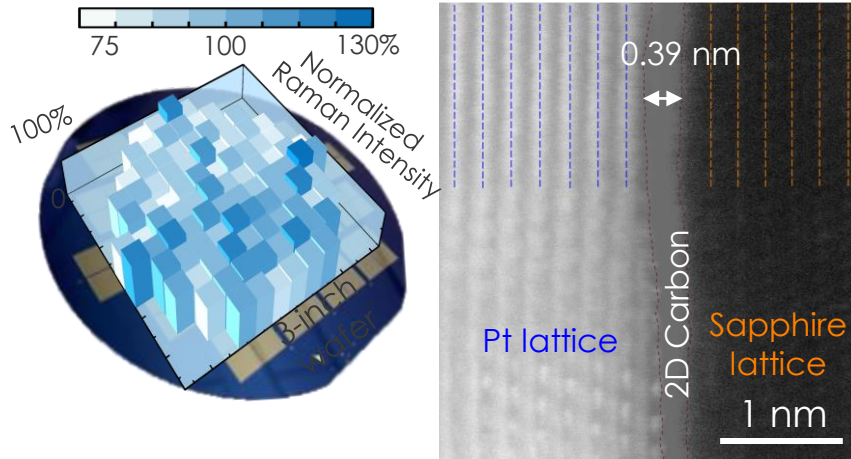


RMS \sim 2 nm.

Wafer-Scale Uniformity and Precise Layer Control

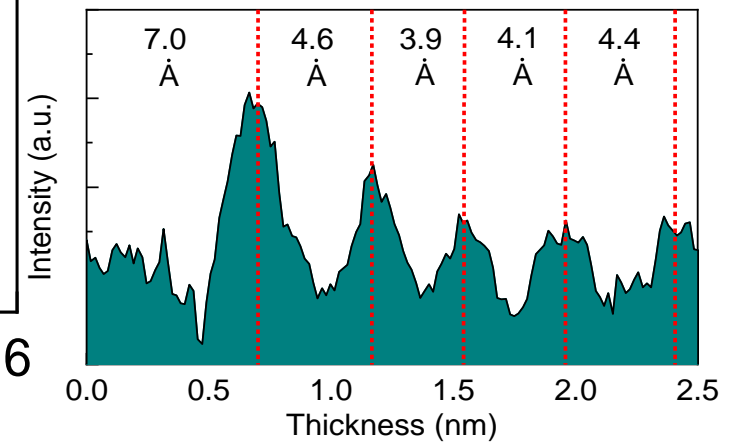
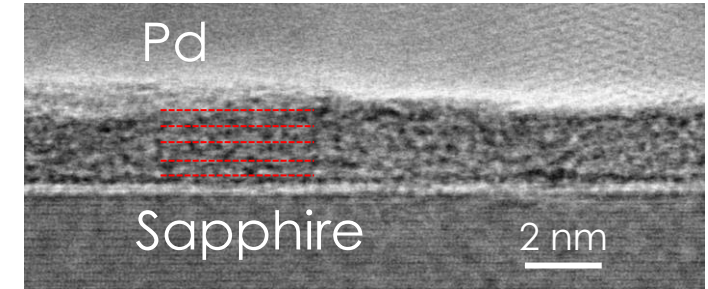
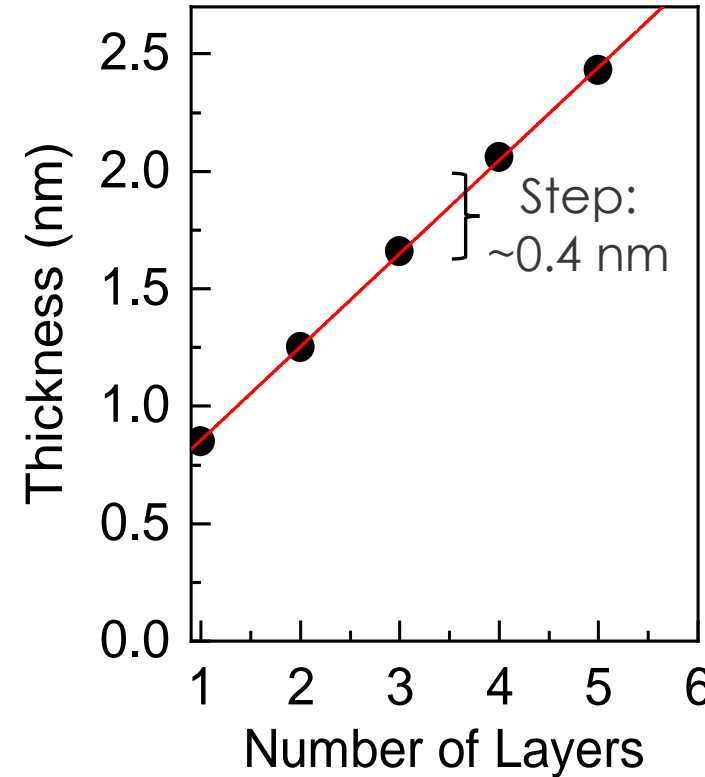
Low-Cost, Scalable Method of 2D Amorphous Carbon Fabrication

Atomically uniform thickness



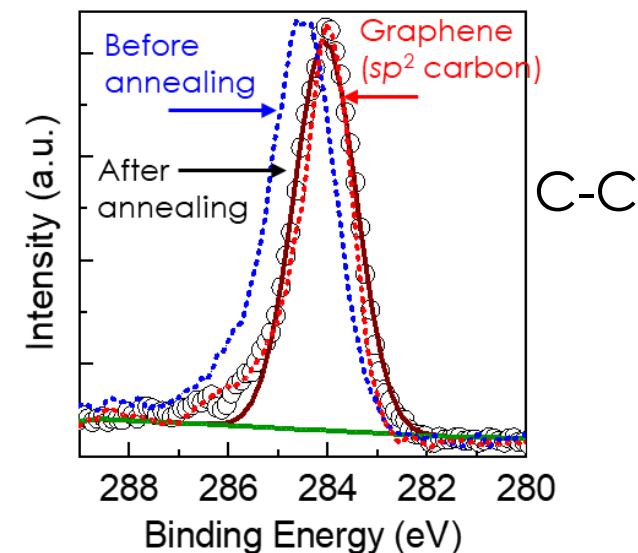
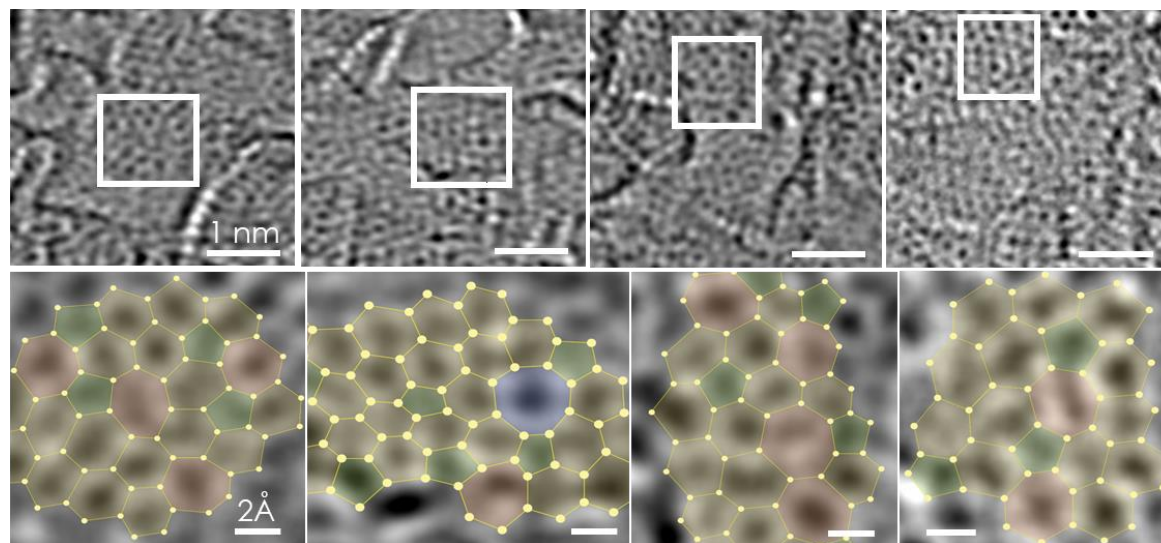
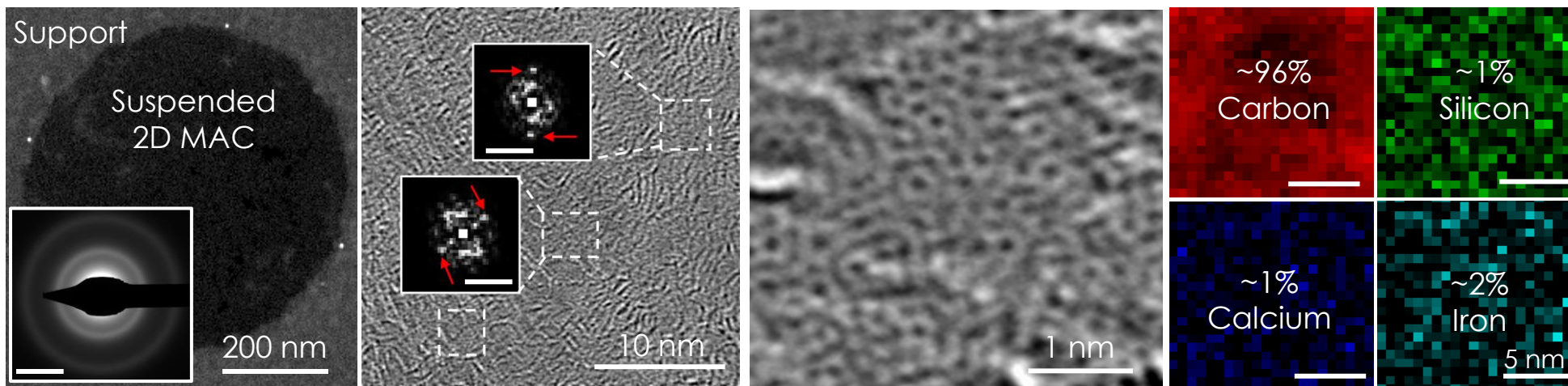
Efficient transfer to different substrates.

Monolayer by monolayer deposition



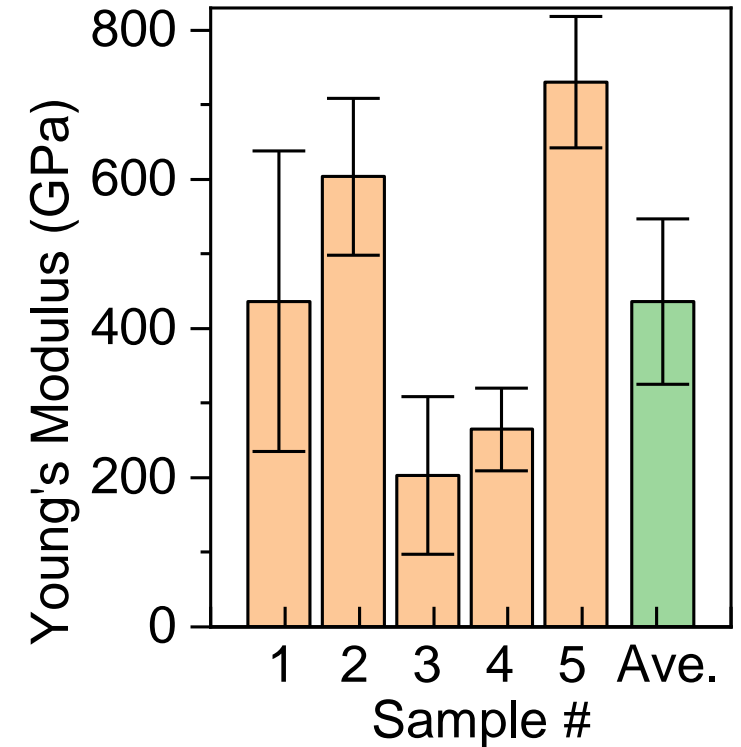
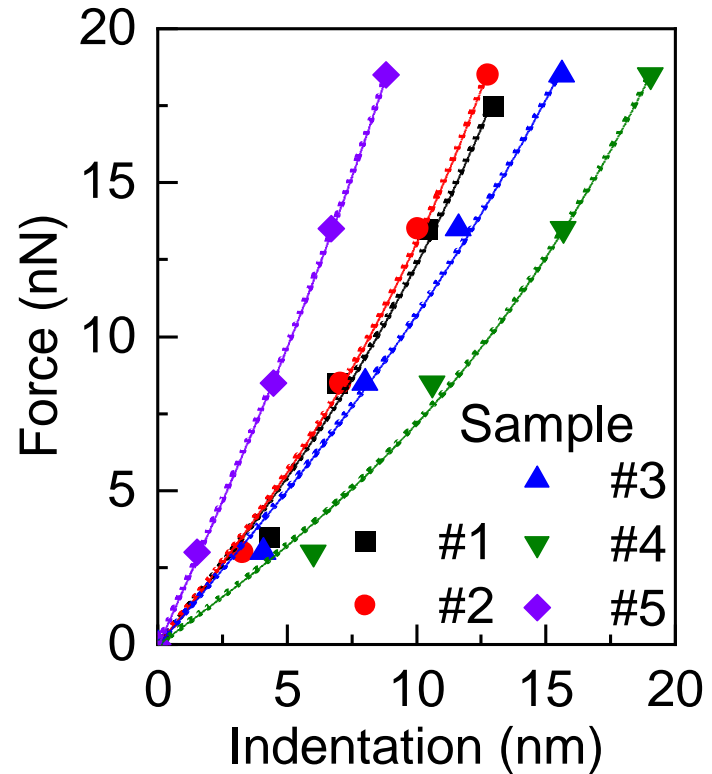
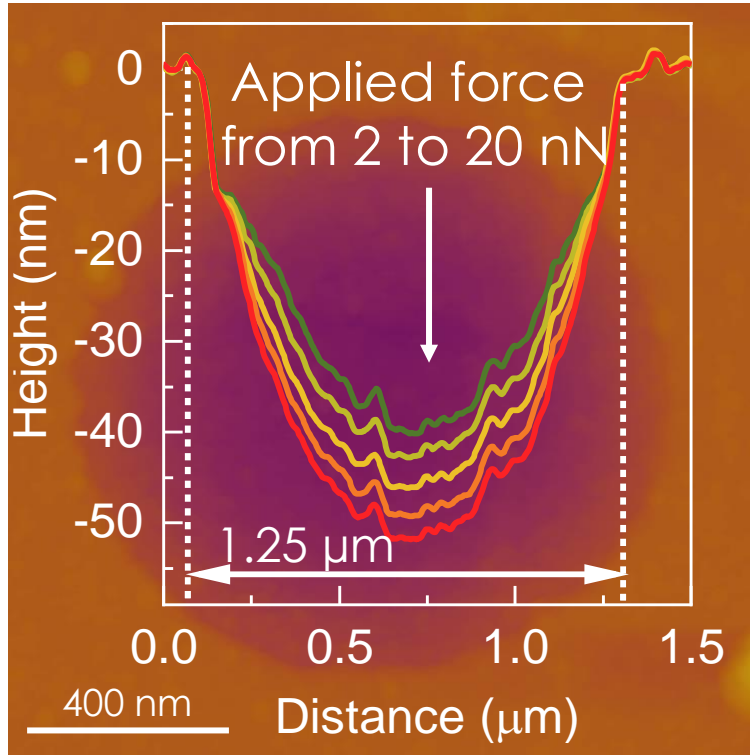
Amorphous Atomic Structures of the 2D Carbon

Large Area, Continuous 2D Amorphous Carbon



Mechanical Properties of 2D Amorphous Carbon

Young's Modulus Comparable to That of Crystalline Graphene

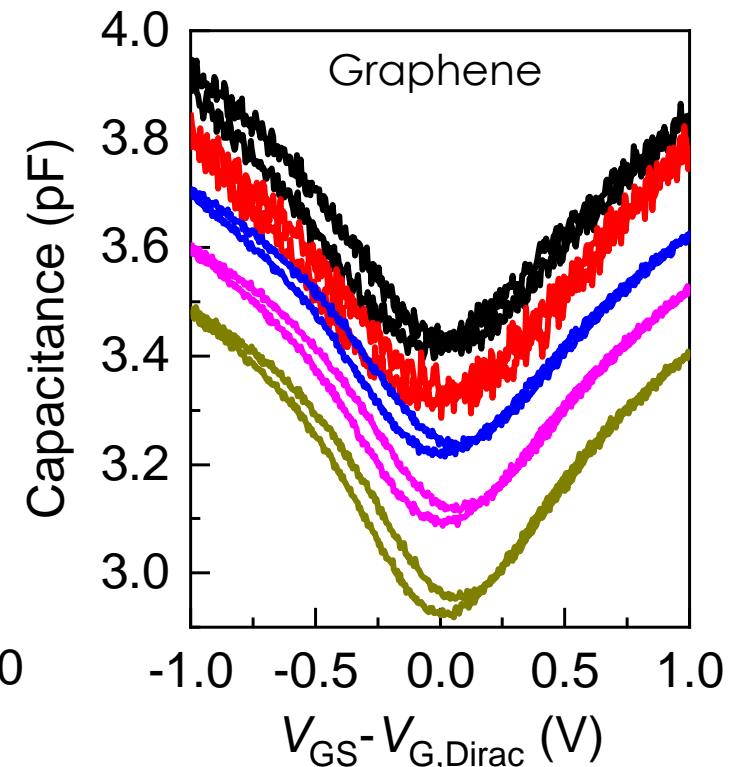
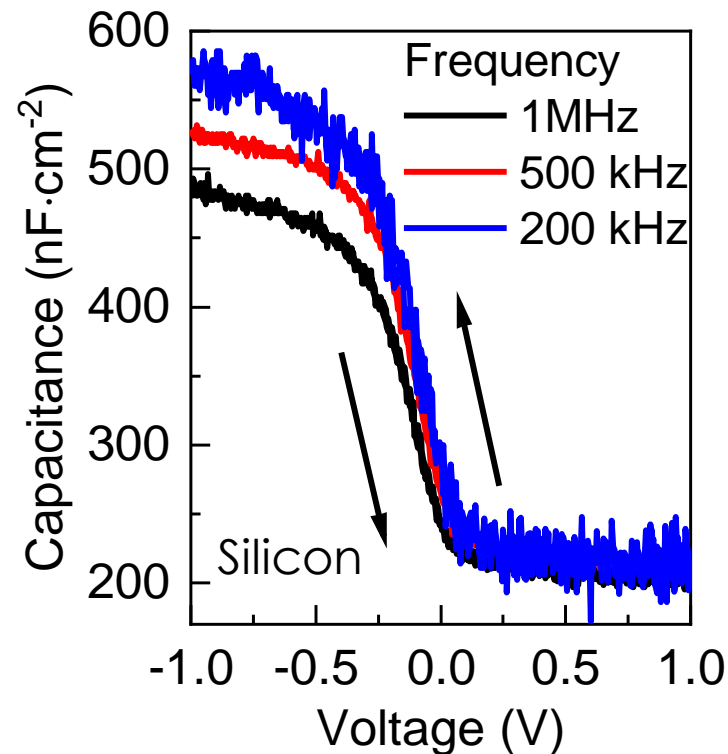
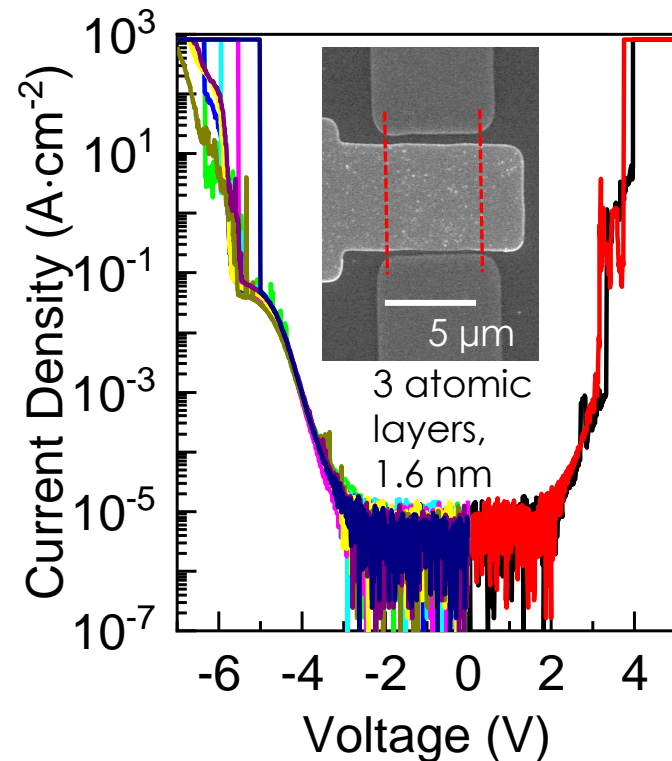


Electrical Properties of 2D Amorphous Carbon

Exceptional Electrical Properties

Low leakage current $<10^{-4} \text{A/cm}^2$ (1000x lower than boron nitride (BN)) high breakdown field $>20 \text{ MV/cm}$ (2x higher than BN)

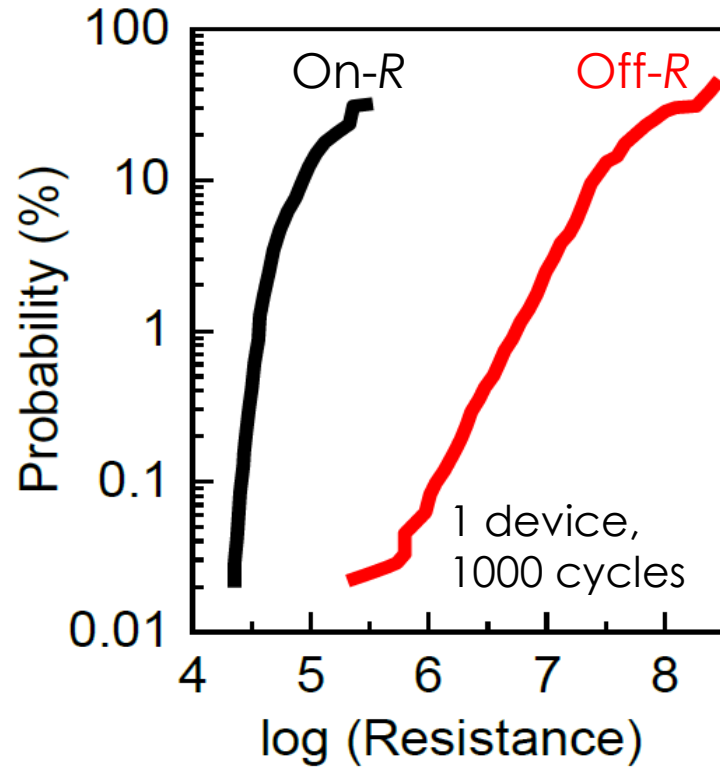
Good interface with Si and graphene (no hysteresis in cyclic voltammetry (CV) curves)



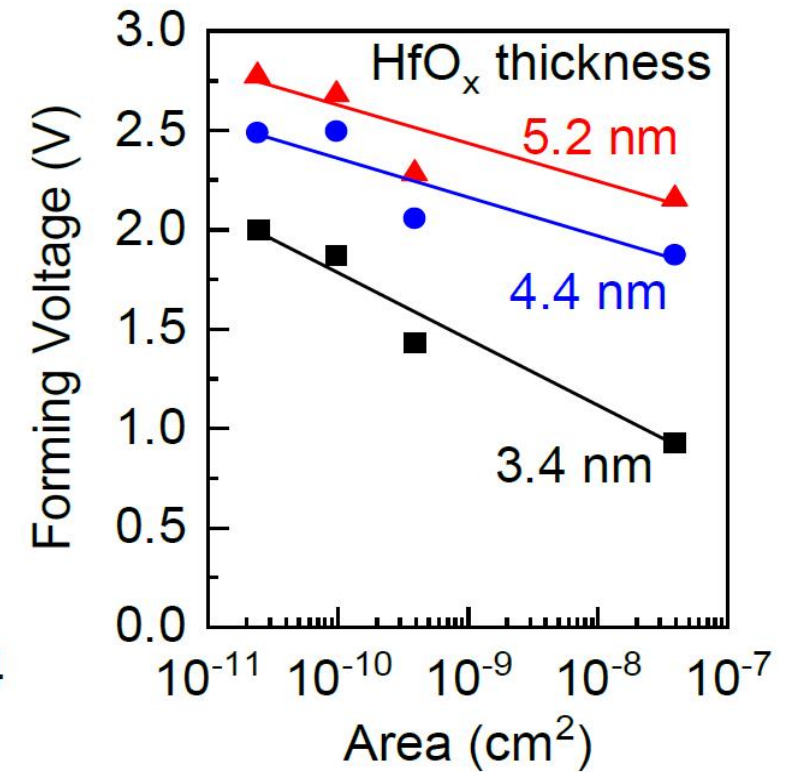
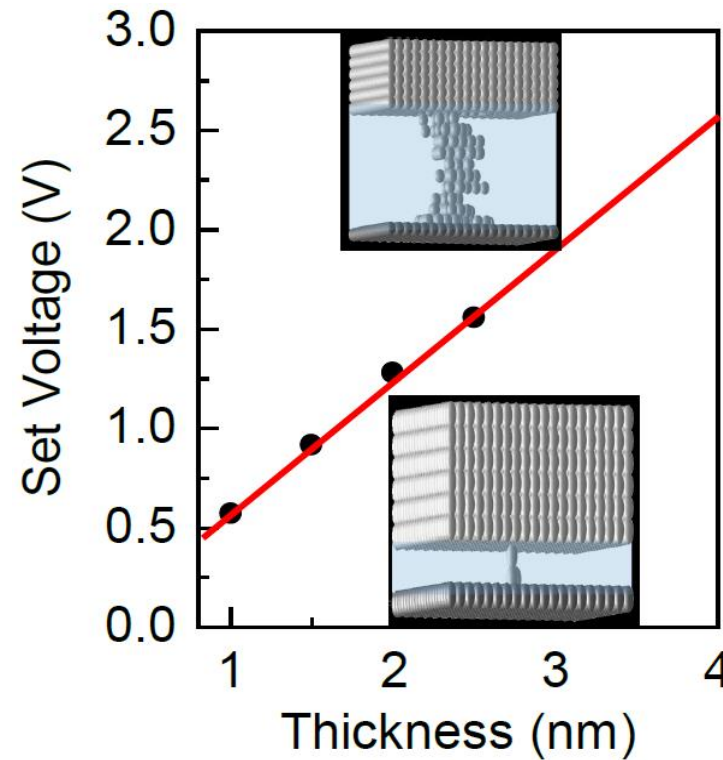
Device Application: Memristor

Significant Problems Limiting Memristor's Commercial Success

High variability (cell-to-cell and cycle-to-cycle)

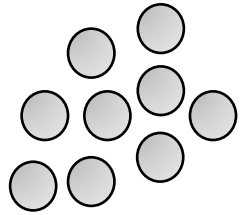


High operation voltage

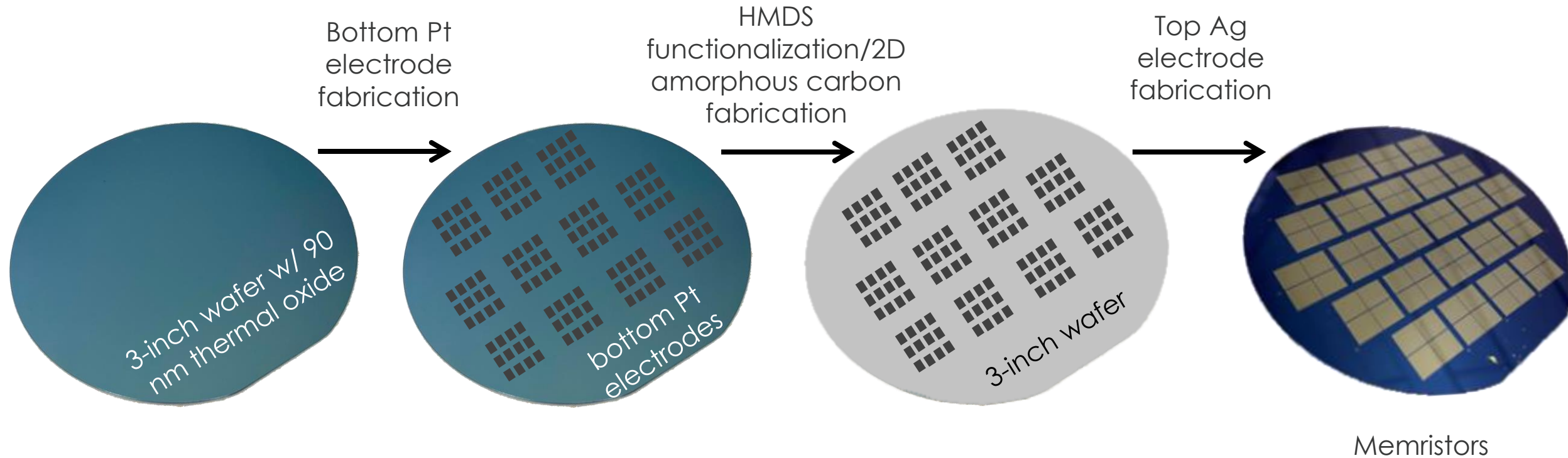


Fabrication of Memristors

Low-Cost Fabrication of 2D Amorphous Carbon Films as Ion-Transport Medium



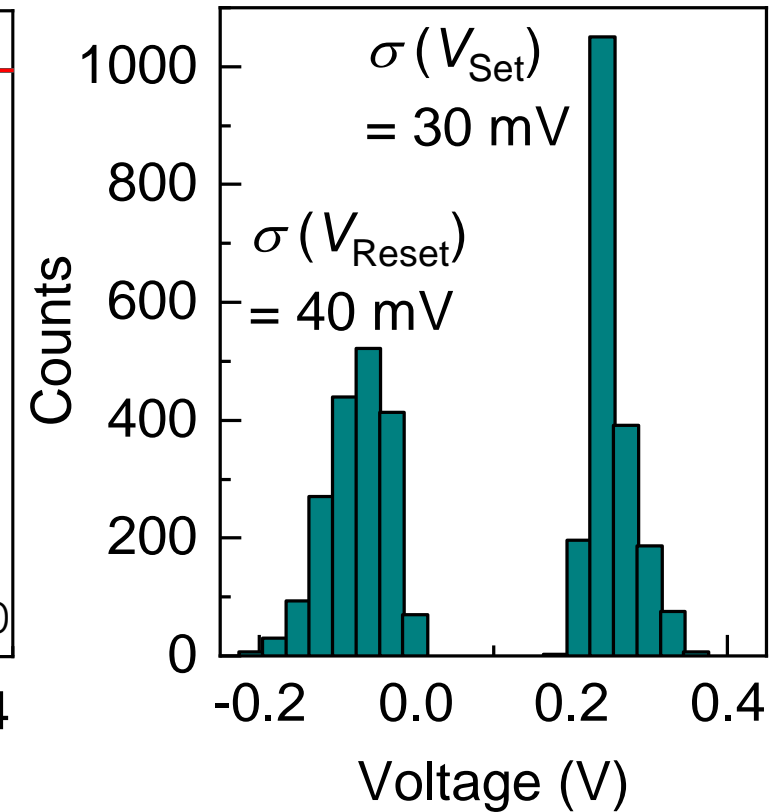
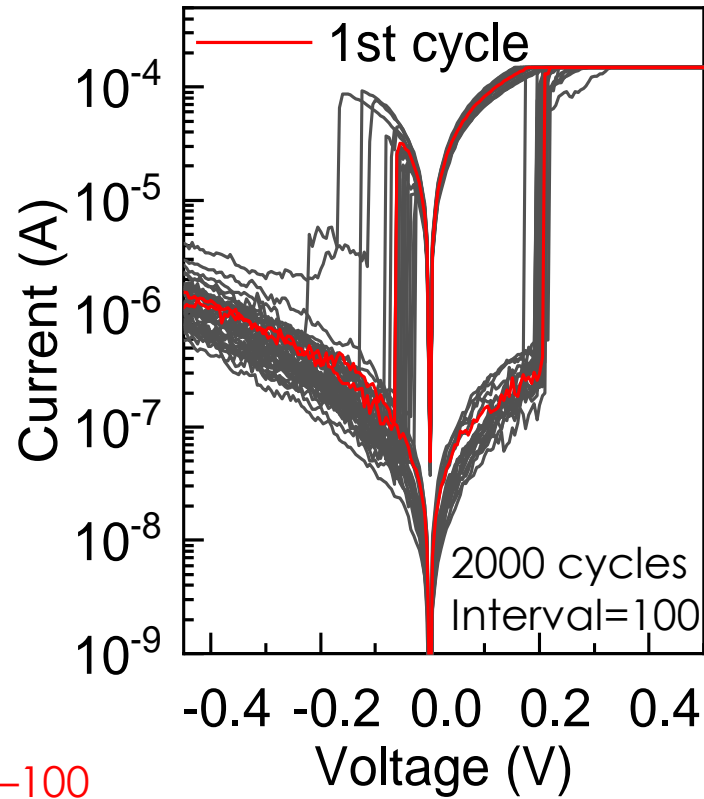
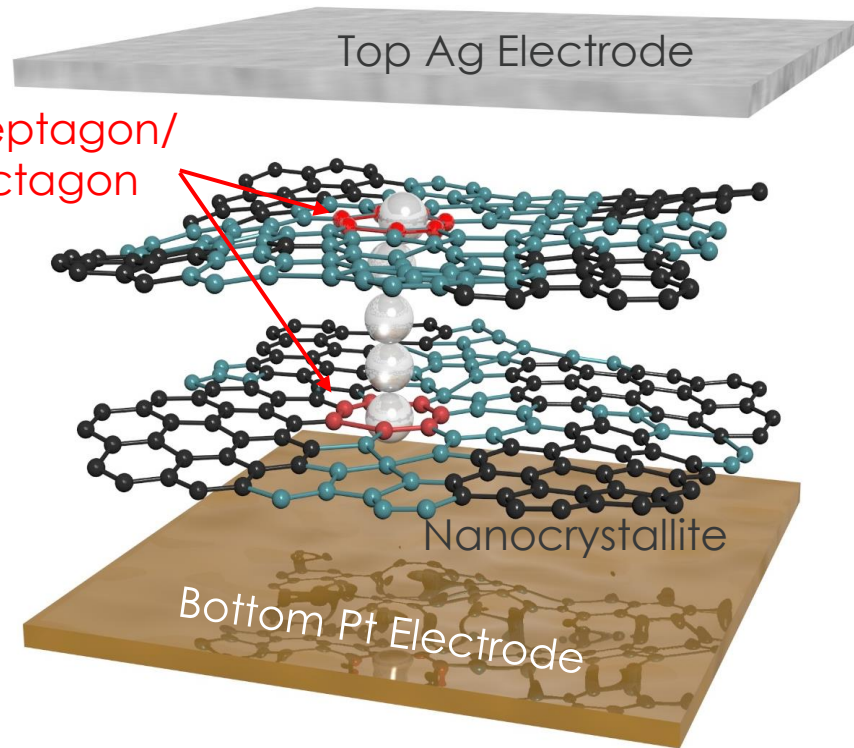
Carbon quantum dot ink



2D Amorphous Carbon for Memristors

Atomically Thin 2D Amorphous Carbon as the Switching Media for Resistive Random-Access Memories (RRAMs)

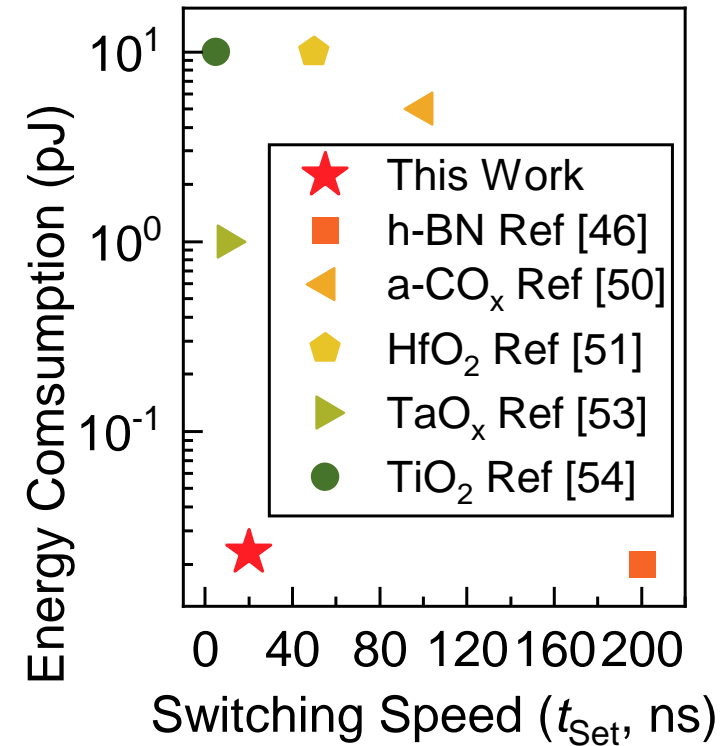
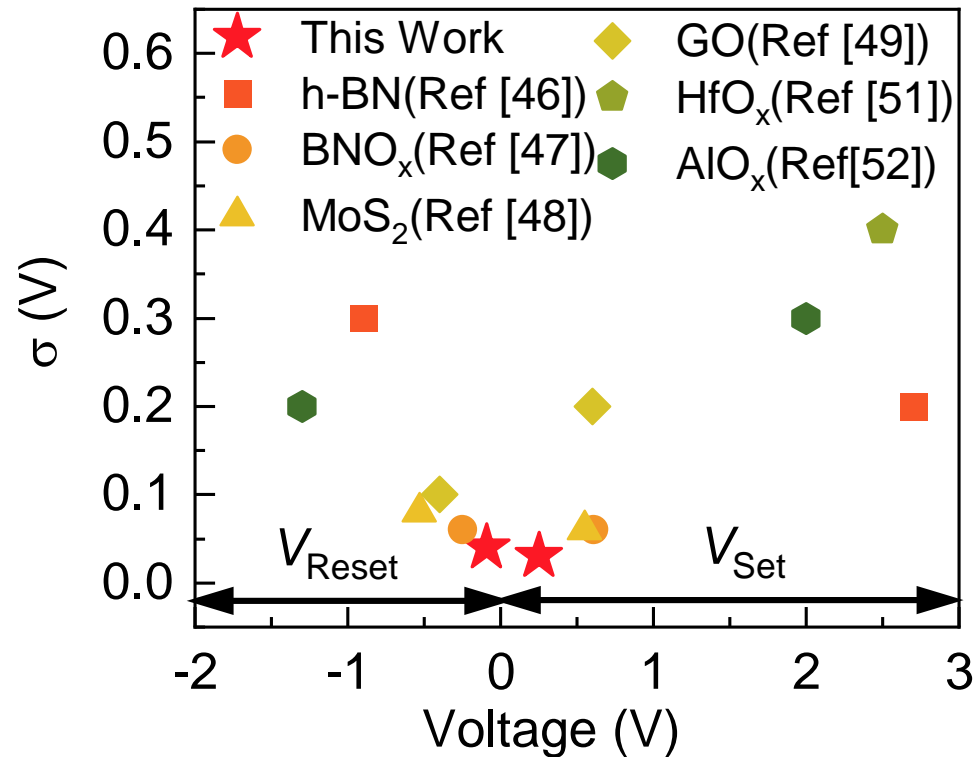
Low operating voltage (<0.4 V), small cycle-to-cycle variability



Energy consumption <20 fJ per operation, 10–100 times lower than the only truly commercial RRAM.

Comparison with Memristor Literature

One of the Best Performing Memristors Enabled by 2D Amorphous Carbon

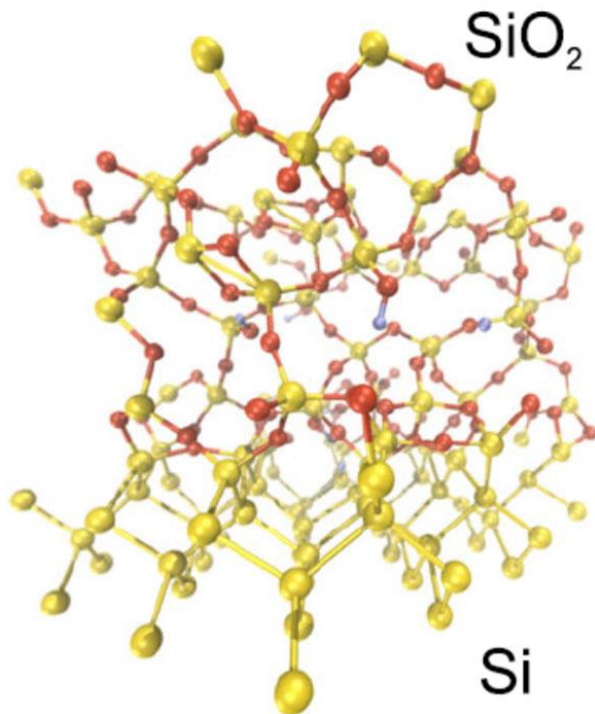


- One of the lowest operation voltage reported (left figure X axis, red stars).
- One of the smallest variations in operation voltage reported (left figure Y axis, red stars).
- One of the fastest and lowest energy consuming devices reported (right figure, red star).

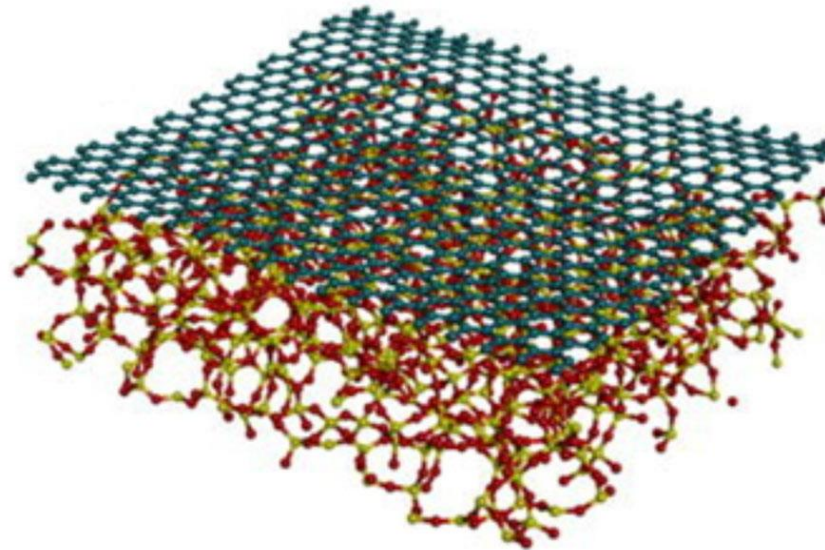
Device Application: Field Effect Transistor (FET)

Existing Dielectric Materials Not Tailored for 2D Electronic Materials

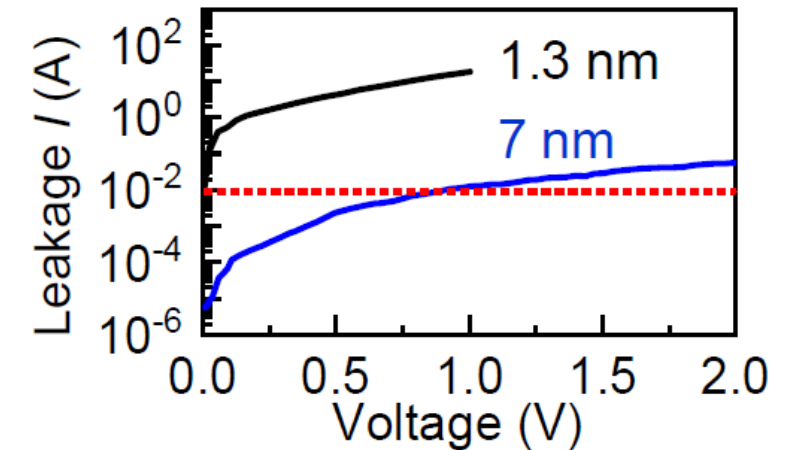
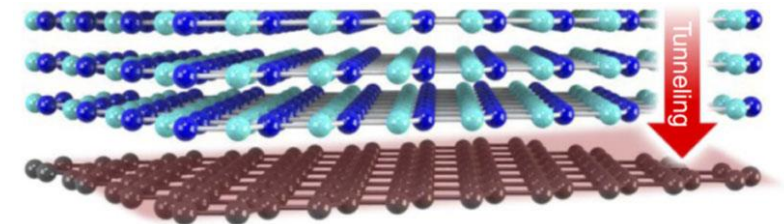
Nearly perfect interface
between Si and SiO₂



High density of traps and scattering
centers at the interface



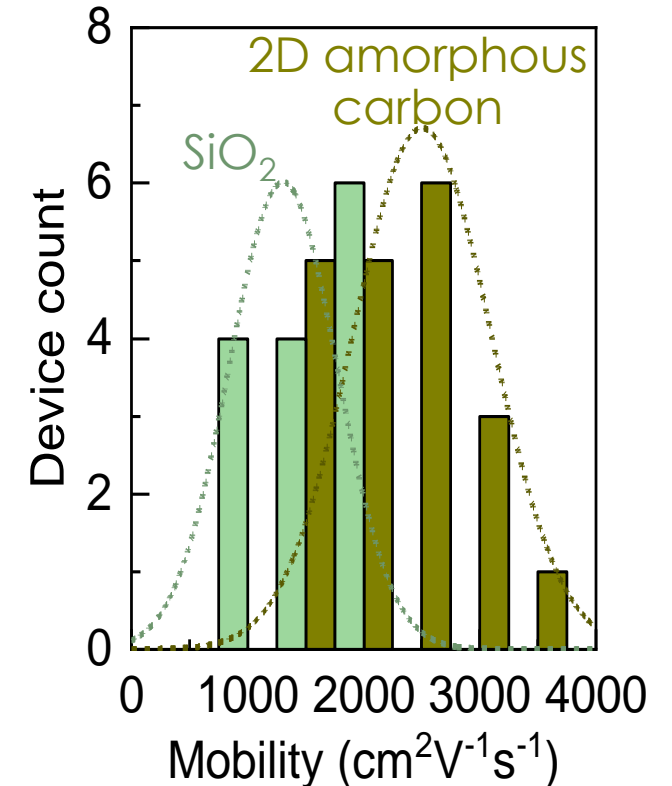
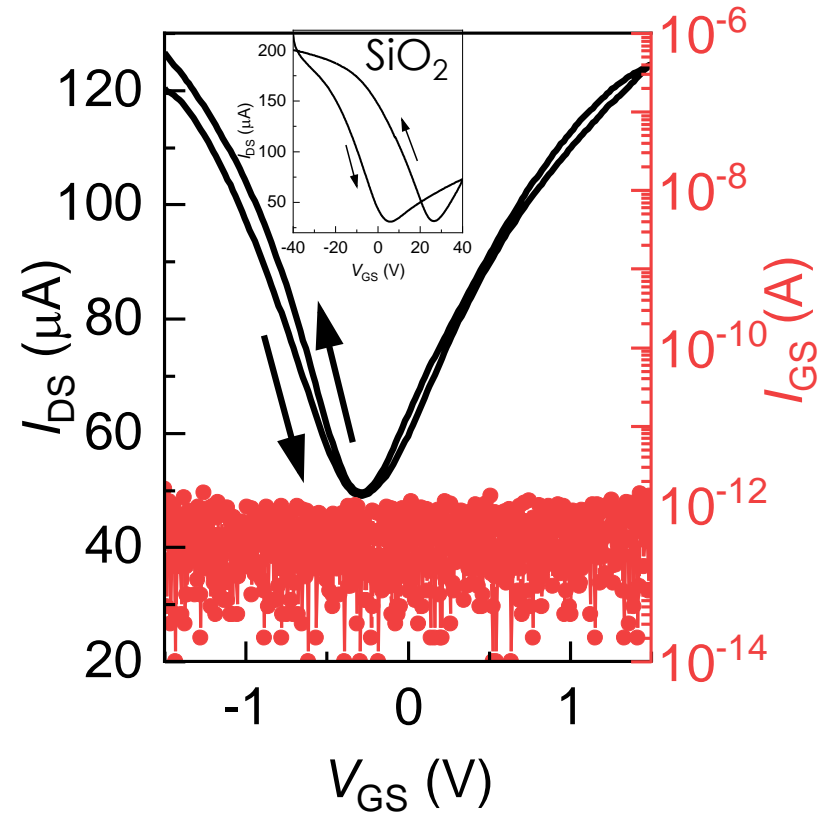
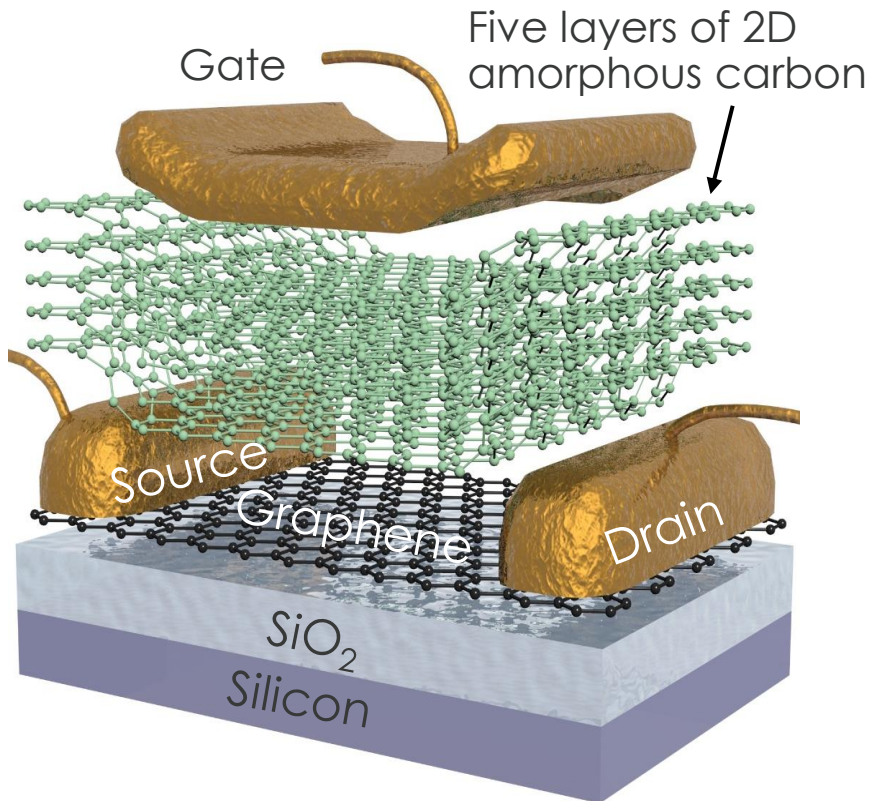
Leakage current through
tunneling and grain boundaries



Nature Commun. **11**, 3385 (2020).
Nature Electron. **4**, 98-108 (2021).

Device Application: Gate Dielectric for Graphene FETs

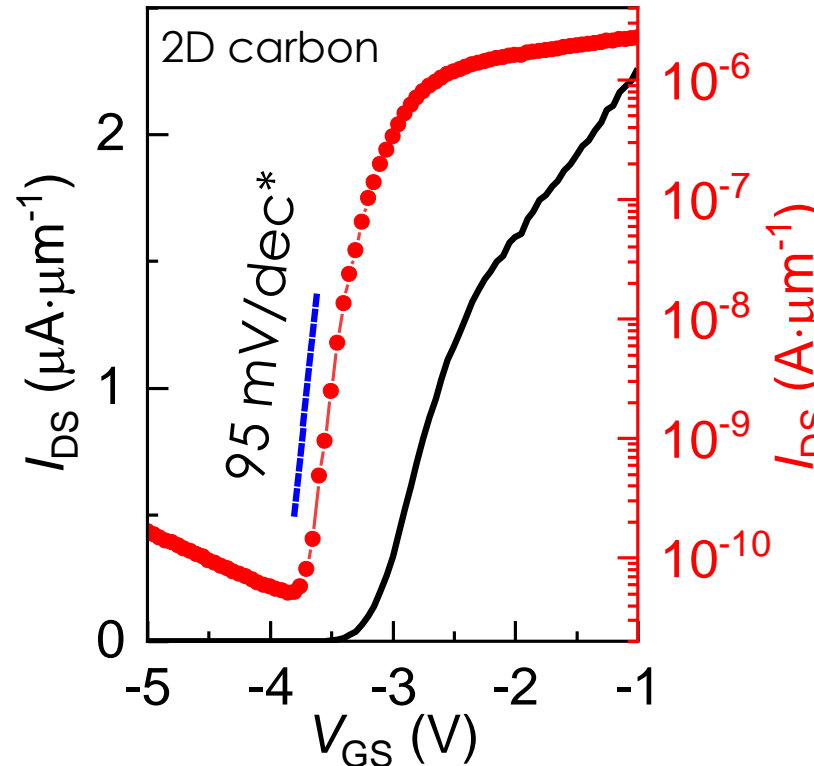
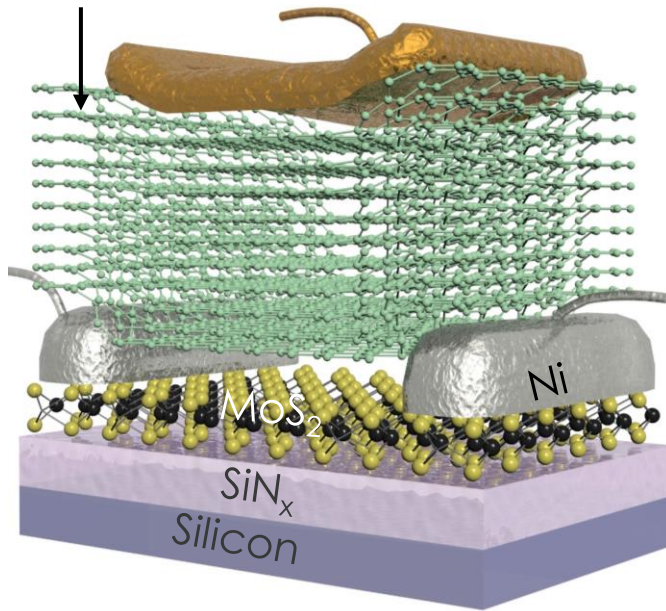
Low Leakage Current, Reduced Hysteresis and Operation Voltage, High Effective Mobility



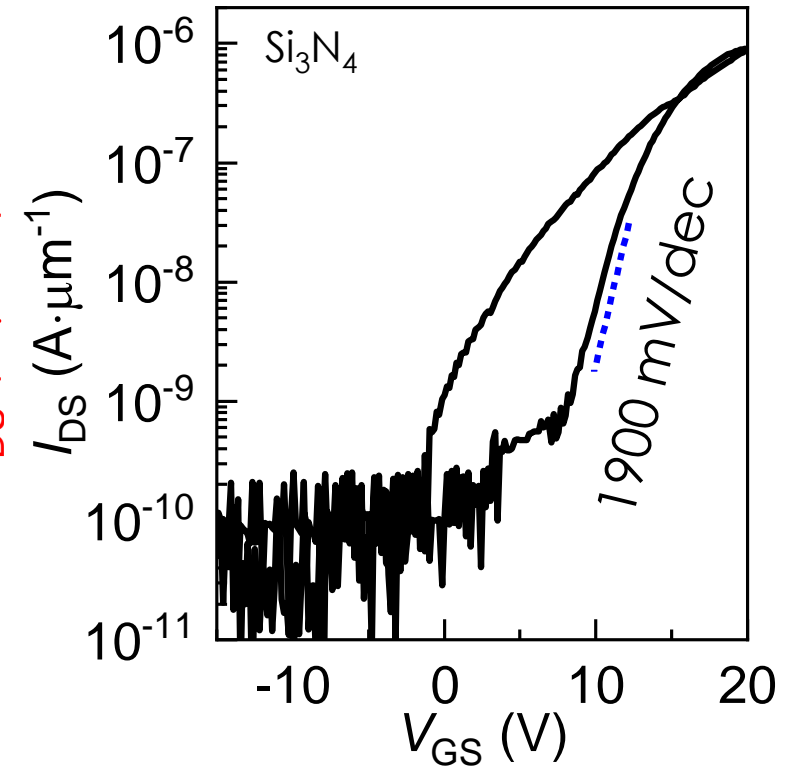
Gate Dielectric for High-Performance 2D MoS₂ Transistors

Reduced Hysteresis and Operation Voltage, Steeper subthreshold swing, High Effective Mobility

Transferred 10 layers of 2D amorphous carbon



$$\mu = 15 \text{ cm}^2\cdot\text{V}^{-1}\cdot\text{s}^{-1}$$



$$\mu = 9 \text{ cm}^2\cdot\text{V}^{-1}\cdot\text{s}^{-1}$$

Summary

Carbon Ore for Advanced Electronic Materials

- Synthesis and control of surface chemistry enable the production of the ideal solution precursor for the scalable fabrication of high performance 2D amorphous carbon.
- 2D amorphous carbon exhibits extraordinary mechanical and electrical properties that can enable next generation solid state electronic devices beyond the limit of existing technology with dramatically improved performance and reduced energy consumption.
- When implemented as the switching layer in memristors, the 2D amorphous carbon enables one of the best performing memristors with ultrafast switching time, low energy consumption, robust endurance, stable data retention, and reduced device spatiotemporal variability.
- Because of the ultrathinness and clean interface with 2D materials, the 2D carbon dielectric leads to dramatically improved device performance that compares favorably against state-of-the-art h-BN and high- κ oxides for FETs.



Communications Engineering 2, 93 (2023).

Acknowledgments



This work was performed in support of the U.S. Department of Energy's (DOE) Office of Fossil Energy and Carbon Management's Carbon Ore Processing Program and executed through the National Energy Technology Laboratory (NETL) Research & Innovation Center's Carbon Ore Processing Multiyear Research Plan.

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